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LIST OF REFERENCES CITED BY APPLICANT

ATTY DOCKET NO.	SERIAL NO.
240669US2	10/624,555
APPLICANT: Yukio TANIGUCHI, et al.	
FILING DATE: July 23, 2003	GROUP: 1756

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA	2004/0126674 A1	07/01/2004	Yukio TANIGUCHI, et al.			
	AB	2004/0061149 A1	04/01/2004	Masayuki JYUMONJI, et al.			
	AC	2003/0099264 A1	05/29/2003	Marcos DANTUS, et al.			
	AD	2004/0266080 A1	12/30/2004	Masayuki JYUMONJI, et al.			
	AE	2004/0142544 A1	07/22/2004	Yoshinobu KIMURA, et al.			
	AF	2004/0161913 A1	08/19/2004	Ritsuko KAWASAKI, et al.			
	AG	2002/0104750 A1	08/08/2002	Hiroshi ITO			
	AH	6,734,635 B2	05/11/2004	Masafumi KUNII, et al.			
	AI	2003/0231663 A1	12/18/2003	Tomoko OHTSUKI, et al.			
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	AW	Wen-Chang YEH, et al., "Effects of a Low-Melting-Point Underlayer on Excimer-Laser-Induced Lateral Crystallization of Si Thin-Films", Jpn. J. Appl. Phys., vol. 40, no. 5A, May 2001, pages 3096-3100
	AX	Y. SANO, et al., "Highly Packed and Ultra-Large Si Grains Grown by a Single-Shot Irradiation of Excimer-Laser Light Pulse", Department of Physical Electronics, Tokyo Institute of Technology, 8 pages
	AY	
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☐ Additional References sheet(s) attached

Examiner: A. Pompey

Date Considered: 6/30/05

*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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	AA	2004-0036969	02/26/04	TANIGUCHI et al.			
	AB	2004-0005744	01/08/04	TANIGUCHI et al.			
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Examiner: E. Crasco — Date Considered: 6/30/05

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Form PTO 1449 (Modified)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY DOCKET NO.	SERIAL NO.
LIST OF REFERENCES CITED BY APPLICANT		240669US2	New Application
		APPLICANT: Yukio TANIGUCHI, et al.	
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OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

	AW	Masakiyo MATSUMURA, "PREPARATION OF ULTRA-LARGE GRAIN SILICON THIN-FILMS BY EXCIMER-LASER", Surface Science, Vol. 21, No. 5, pp. 278-287, 2000, (pgs. 34 - 43)
	AX	M. NAKATA, et al., "TWO-DIMENSIONALLY POSITION-CONTROLLED ULTRA-LARGE GRAIN GROWTH BASED ON PHASE-MODULATED EXCIMER-LASER ANNEALING METHOD", Department of Physical Electronics, Tokyo Institute of Technology, Electrochemical Society Proceedings Vol. 2000-31, (-5- pgs)
	AY	
	AZ	☐ Additional References sheet(s) attached

Examiner: L. Rosario — Date Considered: 6/30/05

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AR	AV	W. YEH, et al., Jpn. J. Appl. Phys., vol. 41, Part 1, no. 4A, pages 1909-1914, "PROPOSED SAMPLE STRUCTURE FOR MARKED ENLARGEMENT OF EXCIMER-LASER-INDUCED LATERAL GRAIN GROWTH IN Si THIN FILMS", April 2002
	AW	M. NAKATA, et al., Jpn. J. Appl. Phys., vol. 40, Part 1, no. 5A, pages 3049-3054, "A NEW NUCLEATION-SITE-CONTROL EXCIMER-LASER-CRYSTALIZATION METHOD", May 2001
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☐ Additional References sheet(s) attached

Examiner E. Rosasco | Date Considered 6/30/05

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